



Docket No.: N.C. 84,613

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Walton et al.
Appl. No. : 10/644,567
Filed : August 20, 2003
Title : ELECTRON BEAM ENHANCED LARGE AREA DEPOSITION
SYSTEM
Art Unit : Not yet assigned
Examiner : Not yet assigned

Honorable Assistant Commissioner for Patents
Washington, DC 20231

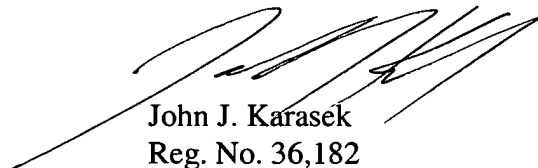
INFORMATION DISCLOSURE STATEMENT

Sir:

Applicants wish to advise the Patent and Trademark Office of the information listed on the attached Form PTO/SB/08 considered during the preparation of the above-identified application. A copy of each of the references listed is enclosed.

Kindly charge any additional fees due, or credit overpayment of fees, to Deposit Account No. 50-0281.

Respectfully submitted,



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PTO/SB/08B (08-00)

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 2 of 2

Complete if Known

Application Number	10/644,567
Filing Date	August 20, 2003
First Named Inventor	Walton et al.
Group Art Unit	Not yet assigned
Examiner Name	Not yet assigned
Attorney Docket Number	84,613

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		R. F. FERNSLER ET AL., "Production of large-area plasmas by electron beams," Phys. Plasmas, 1998, 5, 2137-2143	
		WALLACE M. MANHEIMER ET AL., "Theoretical overview of the large-area plasma processing system (LAPPS)," Plasma Sources Sci. Technol. 2000, 9, 370-386	
		S. G. WALTON ET AL., "Ion energy distributions in a pulsed, electron beam-generated plasma," J. Vac. Sci. Technol. A, 2001, 19(4), 1325-1329	
		D. LEONHARDT ET AL., "Plasma diagnostics in large area plasma processing system," J. Vac. Sci. Technol. A, 2001, 19(4), 1367-1373	
		R. A. MEGER ET AL., "Beam-generated plasmas for processing applications," Phys Plasmas, 2001, 8, 2558-2564	
		KARL-HEINZ MULLER, "Stress and microstructure of sputter-deposited thin films: Molecular dynamics investigations," J. Appl. Phys., 1987, 62, 1796-1799	

Examiner
Signature

Date
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Unique citation designation number. ² Applicant is to place a check mark here if English language Translation is attached.

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Sheet	1	of	2
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U.S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

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¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

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